## Amendments To Claims

1. (Currently Amended) A method for forming a component, comprising the steps of:

forming a set of substructures for the component; forming an airdome structure that encloses the substructures and that provides a set of air spaces for providing isolation among the substructures wherein forming an airdome structure includes forming an overcoat for the airdome structure by filling the air spaces with a gas while depositing the overcoat.

- 2. (Currently Amended) The method of claim 1, wherein the step of forming an airdome structure includes the step of forming the air spaces in the airdome structure.
- 3. (Currently Amended) The method of claim 2, wherein the step of forming the air spaces includes the step of: depositing a layer of dielectric material;

forming a top substructure onto the layer of photoresist dielectric material;

forming a set of gaps in the top substructure; removing the layer of photo-resist dielectric material underneath the top substructure.

- 4. (Currently Amended) The method of claim 3, wherein the step of forming an airdome structure forming an overcoat includes the step of depositing an the overcoat on the top substructure such that the overcoat seals the gaps and encloses the air spaces.
- 5. (Currently Amended) The method of claim 4, wherein the step of depositing an the overcoat includes the step of depositing a dielectric material.

- 6. (Currently Amended) The method of claim 4, wherein the step of depositing an the overcoat includes the step of depositing a plastic material.
- 7. (Currently Amended) The method of claim 4, wherein the step of depositing an the overcoat includes the step of depositing an organic material.
- 8. (Currently Amended) The method of claim 4, wherein the step of forming a top substructure includes the step of shaping the top substructure to impede the overcoat from entering the air spaces.
- 9. (Currently Amended) The method of claim 8, wherein the step of shaping the top substructure includes the step of shaping the layer of photo-resist dielectric material.
- 10. (Withdrawn) A component, comprising:
   a set of substructures;

an airdome structure that encloses the substructures and that provides a set of air spaces for providing isolation among the substructures.

- 11. (Withdrawn) The component of claim 10, wherein the substructures include a top substructure having a set of gaps.
- 12. (Withdrawn) The component of claim 11, wherein the airdome structure includes an overcoat that seals the gaps and encloses the air spaces.
- 13. (Withdrawn) The component of claim 12, wherein the

overcoat is a dielectric material.

- 14. (Withdrawn) The electronic component of claim 12, wherein the overcoat is a plastic material.
- 15. (Withdrawn) The component of claim 12, wherein the overcoat is an organic material.
- 16. (Withdrawn) The component of claim 12, wherein the top substructure is shaped to impede the overcoat from entering the air spaces during formation.
- 17. (New) A method for forming a component, comprising:
  forming a set of substructures for the component;
  forming an airdome structure that encloses the
  substructures and that provides a set of air spaces for
  providing isolation among the substructures wherein
  forming an airdome structure includes forming a set of
  valleys in the airdome structure and depositing an
  overcoat on the airdome structure such that the valleys
- 18. (New) The method of claim 17, wherein forming an airdome structure comprises:

depositing a layer of dielectric material; forming a top substructure onto the layer of dielectric material;

impede the overcoat from entering the air spaces.

forming a set of gaps in the top substructure; removing the layer of dielectric material underneath the top substructure.

19. (New) The method of claim 18, wherein forming a set of valleys in the airdome structure includes forming a set of V-shaped valleys in the top substructure.

- 20. (New) The method of claim 19, wherein forming a set of V-shaped valleys in the top substructure includes shaping the layer of dielectric material.
- 21. (New) The method of claim 18, wherein depositing an overcoat on the airdome structure includes depositing the overcoat on the top substructure such that the overcoat seals the gaps and encloses the air spaces.
- 22. (New) The method of claim 18, wherein forming a set of gaps includes forming the gaps in response to a viscosity of the overcoat.
- 23. (New) The method of claim 18, wherein forming a set of gaps includes selecting a shape of the gaps to prevent the overcoat from filling the air spaces.
- 24. (New) The method of claim 17, wherein depositing an overcoat includes depositing a dielectric material.
- 25. (New) The method of claim 17, wherein depositing an overcoat includes depositing a plastic material.
- 26. (New) The method of claim 17, wherein depositing an overcoat includes depositing an organic material.